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J. Ritter
PATENTS

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
SATOSHI KITAGAWA
Filed: **October 25, 2000**
For: **MARKING METHOD FOR
SEMICONDUCTOR WAFER**

INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents
Washington, DC 20231

Sir:

The citation of information on the attached Form PTO-1449, "List of Art Cited by Applicant" is made pursuant to 37 C.F.R. §§ 1.56, 1.97, and 1.98. Copies of each cited item are enclosed.

An English-language translation of the Abstract of each cited document also is enclosed.

The citation of this information does not constitute an admission of priority or that any cited item is available as a reference, or a waiver of any right the

applicant may have under applicable statutes, Rules of Practice in patent cases, or otherwise.

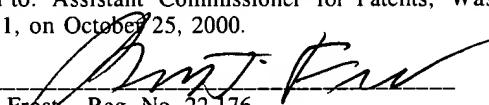
Respectfully submitted,

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I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231, on October 25, 2000.


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